PATENT Serial No: 09/943,262

Docket No: 1743-193

IN THE CLAIMS:

Please amend the claims as follows:

1. (Currently Amended) A scanning charged-particle microscope having a charged-particle source,

a lens for focusing a charged-particle beam emitted from said charged-particle source, and

a scanning deflector for scanning said charged-particle beam in two-dimensional form on a sample,

wherein said scanning charged-particle microscope is characterized in that a passage aperture for limiting the passage of the charged-particle beam is located between the charged-particle source and said scanning deflector, and in that a member for limiting the passage of the charged-particle beam is provided at least in the center of said passage aperture,

said lens focusing the charged particle beam such that a plurality of differential parts of charged particle beam passing through the passage aperture converges one point on the sample <u>simultaneously</u>,

said scanning deflector scanning the converged charged particle beam, and an image of said sample is obtained by scanning said charged-particle beam having passed through said passage aperture on said sample using said scanning deflector.

- 2. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 1 above, wherein the scanning charged-particle microscope is characterized in that has the half-opening angle of said aperture for said charged-particle beam focused on a sample by said focusing lens has a band with respect to specific values of a and b.
- 3. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 1 above, wherein the scanning charged-particle microscope is characterized in that has said passage aperture is formed in a plate-like body, and in that said plate-like body is formed movably with respect to said charged-particle beam.

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4. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 3 above, wherein the scanning charged-particle microscope is characterized in that has said plate-like body is provided with a circular aperture in addition to said passage aperture.

- 5. (Currently Amended) A scanning charged-particle microscope having a charged-particle source,
- a lens for focusing a charged-particle beam emitted from said charged-particle source on a sample with a half-opening angle which defines an irradiation angle of the charged particle beam against an optical axis of the charged particle beam,

a scanning deflector for scanning said charged-particle beam in two-dimensional form on a sample,

wherein said scanning charged-particle microscope is characterized in that it has a member located between the charged-particle source and said scanning deflector, the member having a limiting part which limits the charged particle beam having the half-opening angle being from zero degrees to b degrees and allows the charged-particle beam having the half opening angle being from b degrees to degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees to b degrees beam having the half opening angle being from b degrees to b degrees beam having the half opening angle being from b degrees to b degrees

said lens focusing the charged particle beam such that a plurality of differential parts of charged particle beam having the half opening angle being from b degrees to a degrees converges one point on the sample, simultaneously,

said scanning deflector scanning the converged charged particle beam, and an image of said sample is obtained by scanning said charged-particle beam which is cut off the half opening angle being from b degrees to a degrees.

- 6. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 5 above, wherein the scanning charged-particle microscope is characterized in that has a plate-like aperture body in which an annular aperture is formed is provided between said charged-particle source and said scanning deflector.
- 7. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 6 above, wherein the scanning charged-particle microscope is characterized in

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that <u>has</u> in addition to said annular aperture, a circular aperture is provided in said platelike aperture body, and in that there is provided a movement feature for positioning said annular aperture and said circular aperture on the orbit of said charged-particle beam.

8. (Currently Amended) A scanning charged-particle microscope having a charged-particle source,

a lens for focusing the charged-particle beam emitted from said charged-particle source, and

a scanning deflector for scanning said charged-particle beam in two-dimensional form on a sample,

wherein said scanning charged-particle microscope is characterized in that <u>has</u> an aperture, located between the charged-particle source and said scanning deflector, for limiting the passage of said charged-particle beam is formed in two different places on the orbit thereof, and in that one of said two apertures is an annular aperture and the other is a circular aperture, and

an image of said sample is obtained by scanning said charged-particle beam having passed through said annular aperture on said sample using said scanning deflector.

- 9. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 8 above, wherein the scanning charged-particle is characterized in that in said annular aperture is formed in a plate-like body, in that said plate-like body is also provided with a circular aperture, and in that there is provided a movement feature for positioning the annular aperture and the circular aperture on the orbit of said charged-particle beam.
- 10. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 8 above, wherein the scanning charged-particle microscope is characterized in that in said circular aperture is formed in a plate-like body, in that said plate-like body is also provided with a charged-particle beam cutoff portion, and in that there is provided a movement feature for positioning said charged-particle beam cutoff portion and said circular aperture on the orbit of said charged-particle beam.

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11. (Currently Amended) A scanning charged-particle microscope as set forth in Claim 8 above, wherein the scanning charged-particle microscope is characterized in that has said circular aperture and said annular aperture are formed in a first plate-like body and a second plate-like body, respectively, in that said first plate-like body is provided with a charged-particle beam cutoff portion in addition to the circular aperture and said second plate-like body is provided with a circular aperture in addition to the annular aperture, and in that both the first plate-like body and the second plate-like body are provided with a movement feature.

- 12. (Currently Amended) A samples image forming method using a scanning charged-particle microscope having
 - a charged-particle source,
- a lens for focusing the charged-particle beam emitted from said charged-particle source, and

a scanning deflector for scanning said charged-particle beam in two-dimensional form on a sample,

wherein said samples image forming method is characterized in that has the image of a sample that has been acquired by scanning said charged-particle beam having passed through an annular aperture on said sample using said scanning deflector, said annular aperture being positioned on the orbit of the charged-particle beam and between said charged particle source and said scanning deflector, and the image of a sample that has been acquired with a circular aperture positioned on the orbit of the charged-particle beam are combined to form a new samples image.